

ABSTRACT

The present invention discloses a process tank temperature-measuring device and a substrate processing apparatus. The process tank temperature-measuring device is used for detecting the temperature of a chemical solution in a process tank, and the upper end of the process tank is provided with an opening. The process tank temperature-measuring device comprises: a protective pipe, including a temperature-measuring portion and an extension portion that are sequentially connected and in mutual communication, the end of the temperature-measuring portion away from the extension portion being sealed to form a bottom portion of the protective pipe, the end of the extension portion away from the temperature-measuring portion being opened to form an inlet of the protective pipe, and a preset included angle being formed between the axial direction of the temperature-measuring portion and the axial direction of the extension portion; a temperature-measuring probe, arranged inside the temperature-measuring portion, and positioned at the bottom portion of the protective pipe. Wherein, the bottom portion of the protective pipe is arranged to be immersed in the chemical solution in the process tank, so that the temperature-measuring probe detects the temperature of the chemical solution in the process tank, and the inlet of the protective pipe is arranged offset from directly above the opening of the process tank, thereby realizing the effects of a simple structure and strong corrosion resistance of the process tank temperature-measuring device.